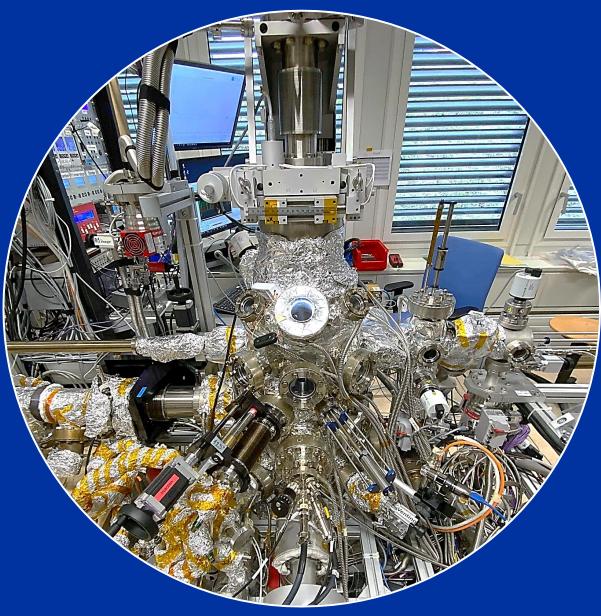




SEY and ESD of ices and technical surfaces at cryogenic temperatures

Michal Haubner TE-VSC-VSM, CERN CTU in Prague, CZ

V. Baglin, B. Henrist TE-VSC-VSM, CERN



Research motivation

Technical-grade metal surfaces

Polycrystalline, oxidized, porous, contaminated

Electron irradiation

Thermionic e-

Multipacting e-

Runaway e⁻

Cosmic radiation

• • •

Cryogenic temperatures

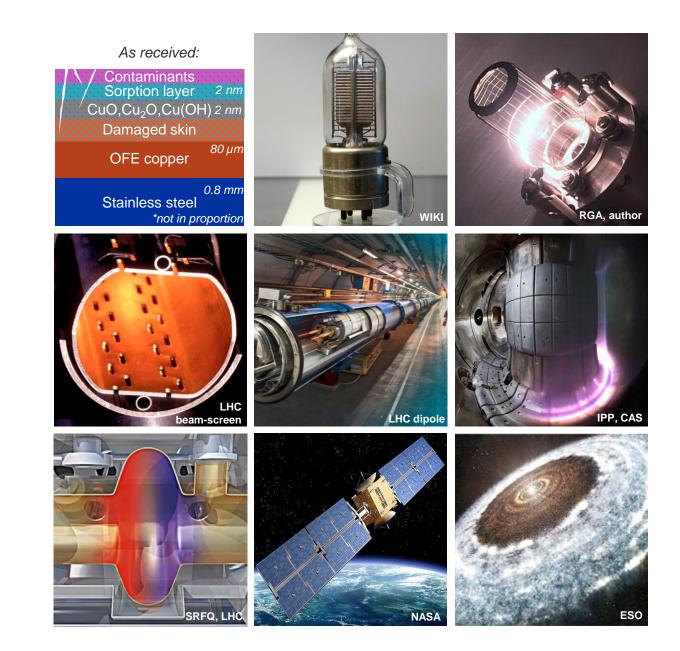
Low diffusion rates

Cryosorbed gases

Cross-disciplinary interest

LHC-oriented

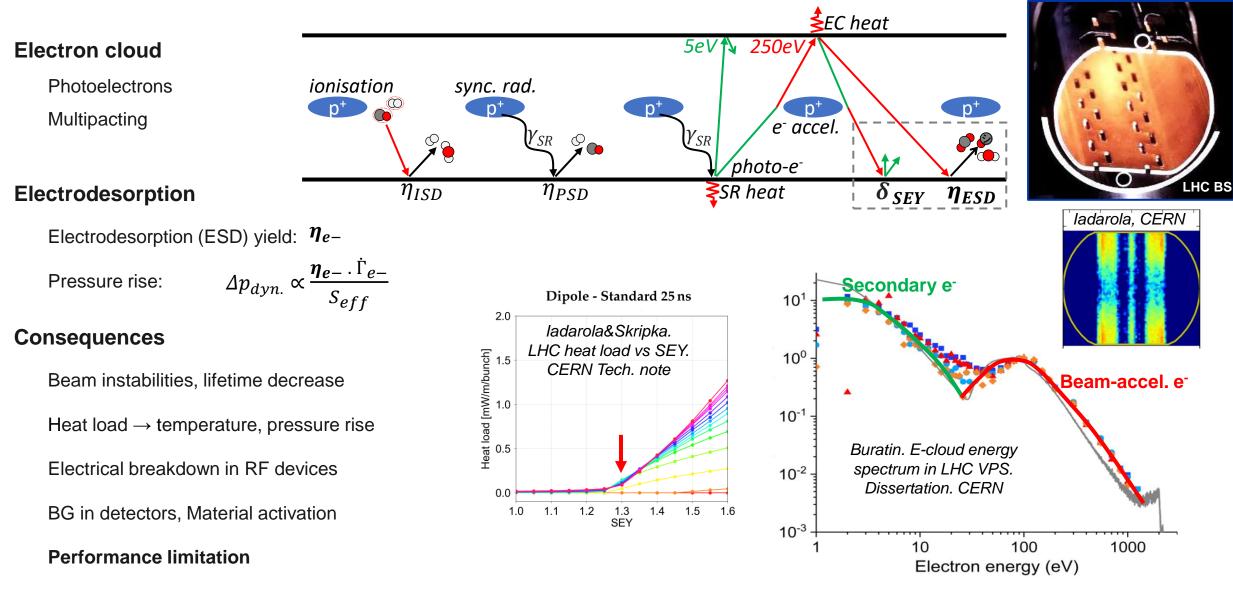
Other machines & applications





Dynamic vacuum effect in LHC

e⁻CLOUD'22



Parameters influencing the SEY and ESD

Material surface state:

- Surface composition
- Treatments & Coatings
- Cleaning
- Contamination
- Storage

. . .

٠

backscattered primary electrons electrons (BSE) true secondary desorbing gas electrons (SE) and fragments vacuum ≈ ps adsorbed gas Do C surface / SE escape depth ≈ nm e scattering (slowing down) ≈ fs range heat dissipation excitation volume ≈ ps (e⁻ thermalization) bulk material ≈ 100 fs

Electron irradiation:

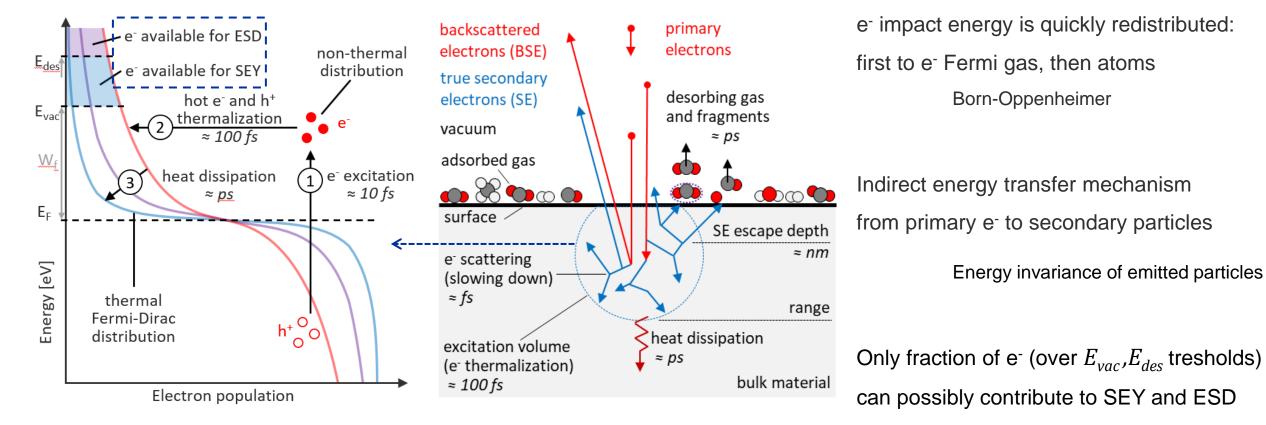
- Energy
- Dose
- Angle

Environment:

- Temperature
- Adsorbed gases



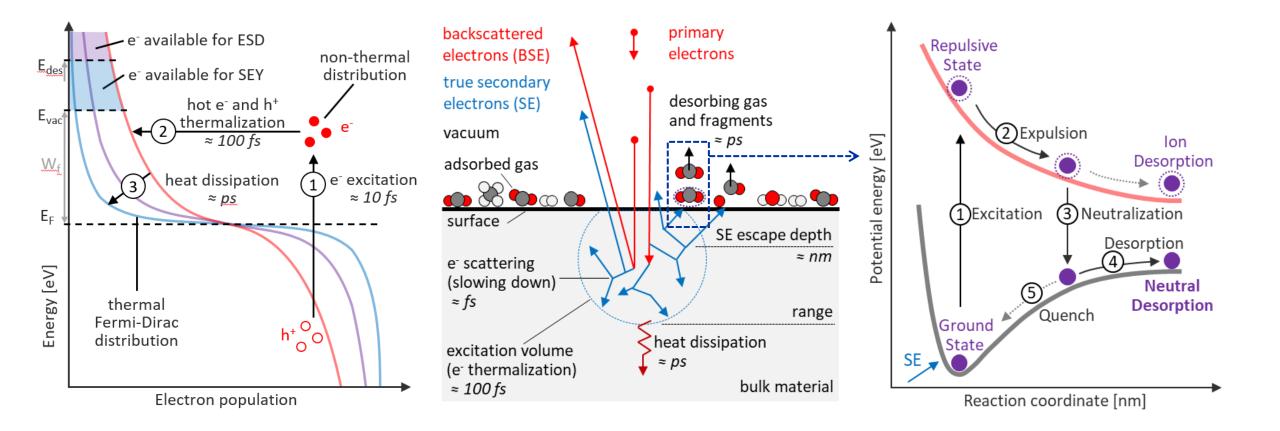
Electron and molecule emission



```
\eta_{e} \propto 1 / E_{BOND}
```



Electron and molecule emission





Experimental setup description

Cu/SS SS a-C beam-screen Thermal shield Cold sample Collector Energy scan

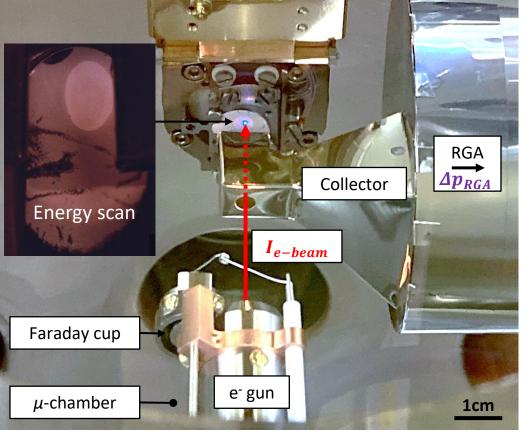
SEY, ESD, TPD capability at cold

Controllably reproduce LHC-like conditions:

10 K - 300 K	$T_{BS} = 5 - 20 K$
10 ⁻¹¹ mbar	hours till 1 Langmuir (10 ⁻⁶ Torr.s)
0 - 1.5 keV	E-cloud spectrum
no B-field	µ-metal chamber

Experimental targets:

10 ⁻⁶ - 10 ³ molecule/e ⁻	ESD sensitivity
Cu, SS, Al,	Unbaked metals
a-Carbon, LESS, NEG	Coatings and treatments
N ₂ , CO, CO ₂ , CH ₄ , Ar,	Cryosorbed gases





ESD and SEY measurement

ESD yield:

$$\eta_{e,j}(E,D) = \frac{C_j \Delta p_j}{k_B T} / \frac{I_B}{q_e} + \frac{C_j \Delta p_{j,BG}}{k_B T} / \frac{I_C}{q_e}$$

Signal + Dynamic BG
$$\delta(E,D) = \frac{I_{SE}}{I_B} = \frac{I_C}{I_C + I_S}$$

Collector

SEY:

Closed geometry to capture molecules and e-

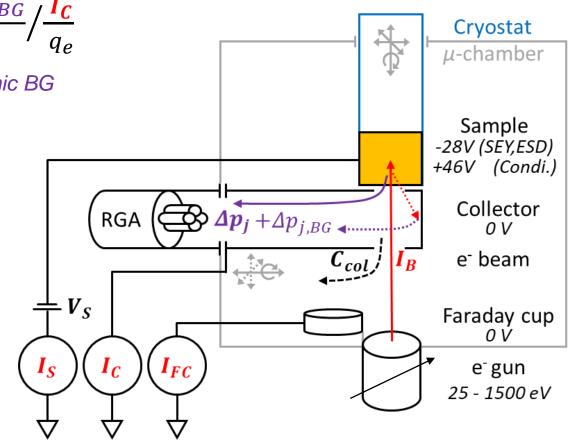
Simultaneous SEY and ESD measurement

Conductance-limited pumping, defined by geometry

Gas dosing possibility

Low-energy

Retarding sample bias to reach 0 eV





SEY measurement

Secondary electron yield:

Engineering relevance

LHC e⁻ multipacting limit

Similar SEY shape between conditioned Cu, a-C & HOPG

Mean of calibration

Set energy scale, verify resolution HOPG reference – Checks with other labs HOPG bands imprint onto the LE-SEY

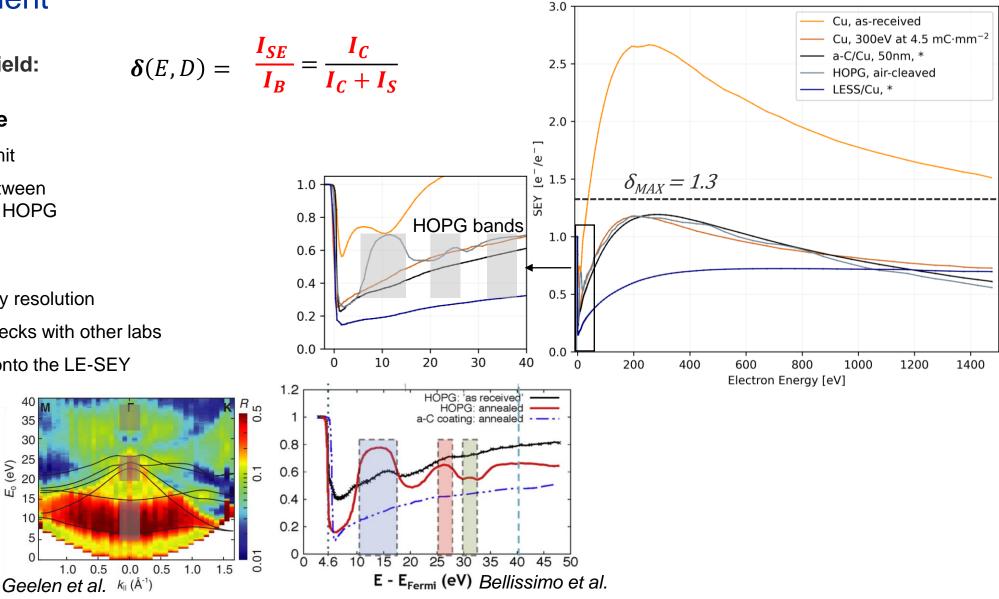
> 35 30

(^25 20

15 10

1.0 0.5

щ





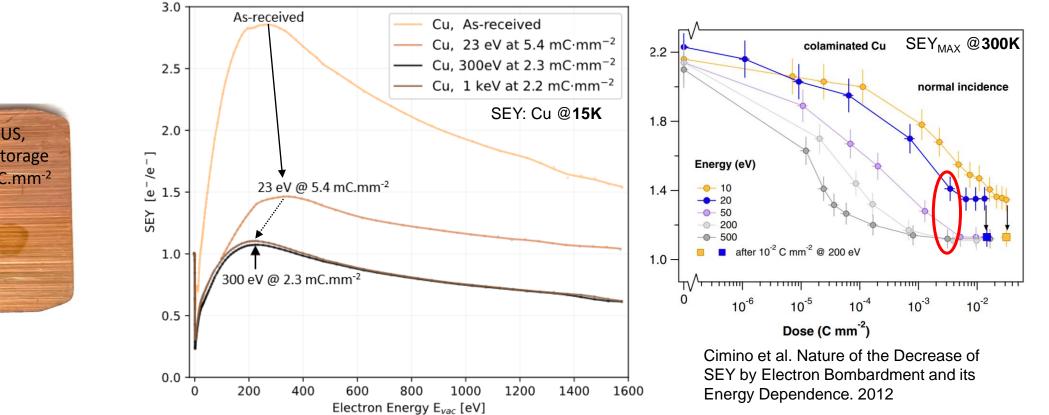
SEY: Cold Cu conditioning at low and high energy

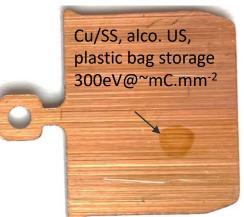
Conditioning Decrease of SEY and ESD with e⁻ dose

SEY scrubbing: Depletion of adsorbed gas & formation of a graphitic layer

High energy electrons are necessary for graphitization.

Known at 300K \rightarrow **Same story at 15K**, confirmed by C_{1s} peak on XPS





e-CLOUD'22



SEY: Warm Cu conditioning vs initial surface state

Conditioning

Decrease of SEY and ESD with e⁻ dose

SEY scrubbing: Depletion of adsorbed gas & formation of a graphitic layer

Surface-bound carbon is necessary for graphitization

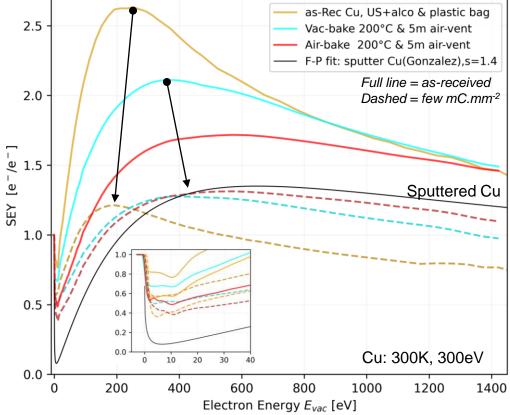
As-received shape indicates a graphitization potential, $E_{MAX} \approx 200 \text{ eV}$

"Carbon c'est bon" Nishiwaki & Kato. (2009). Graphitization of inner surface of copper beam duct of KEKB positron ring. Vacuum.



Scheuerlein et al. 2002. An AES study of the room temperature conditioning of technological metal surfaces by electron irradiation. Applied Surface Science.

e-CLOUD'22



SEY: Cold Cu conditioning vs residual gas composition

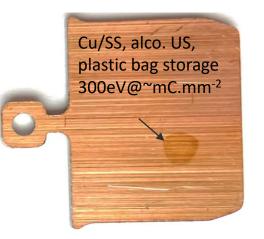
Conditioning

Decrease of SEY and ESD with e⁻ dose

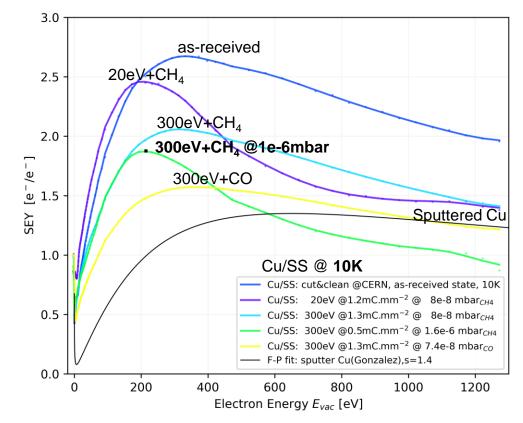
SEY scrubbing: Depletion of adsorbed gas & formation of a graphitic layer

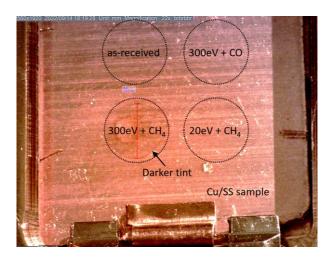
The carbon-rich residual gas is insufficient to aid graphitization at this setting (at UHV and 10K)

"Carbon c'est bon" Nishiwaki & Kato.. (2009). Graphitization of inner surface of copper beam duct of KEKB positron ring. Vacuum



Scheuerlein et al. 2002. An AES study of the room temperature conditioning of technological metal surfaces by electron irradiation. Applied Surface Science





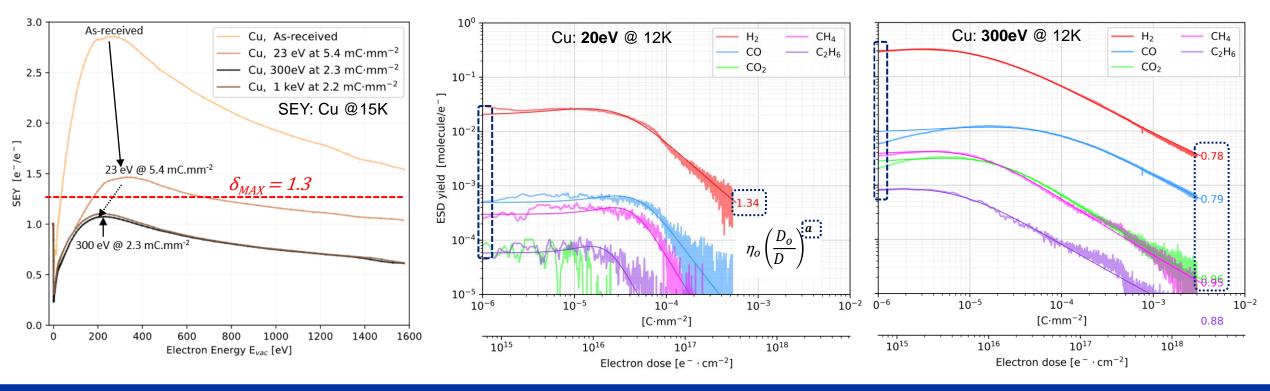
Loose follow-up on a 300K study: Scheuerlein & Taborelli. Electron stimulated carbon adsorption in ultrahigh vacuum monitored by AES. *JVST-A*, 2002.



ESD: Cold Cu conditioning at low and high energy

- **Conditioning** Decrease of SEY and ESD with e⁻ dose
 - SEY scrubbing Depletion of adsorbed gas & formation of graphitic layer
 - ESD conditioning: Depletion of adsorbed gas

Lower ESD yield at high e^- dose \rightarrow Lower pressure rise due to e-cloud





ESD: Cold Cu conditioning at low and high energy

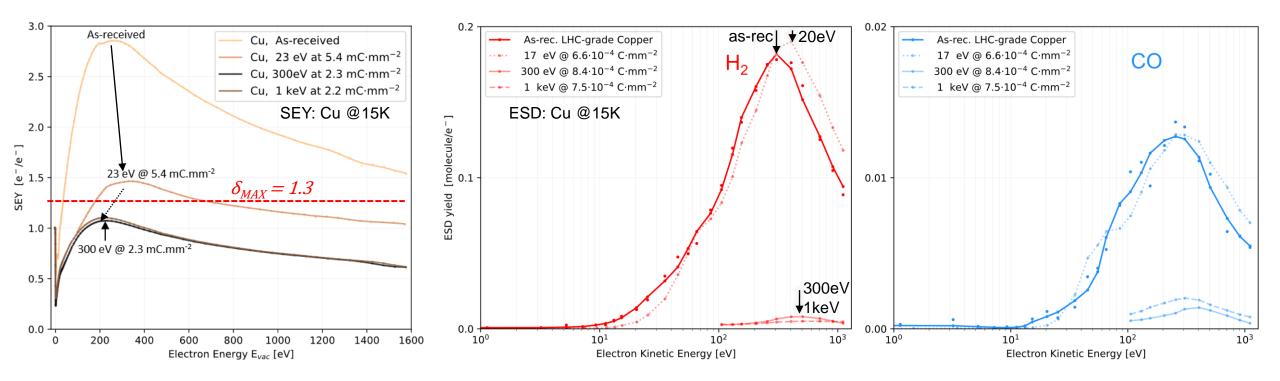
Conditioning Decrease of SEY and ESD with e⁻ dose

SEY scrubbing Depletion of adsorbed gas & formation of graphitic layer

ESD conditioning: Depletion of adsorbed gas

Lower ESD yield at high e^- dose \rightarrow Lower pressure rise due to e-cloud

20 eV do little - 300 eV conditions best - 1 keV is not proportionally more efficient

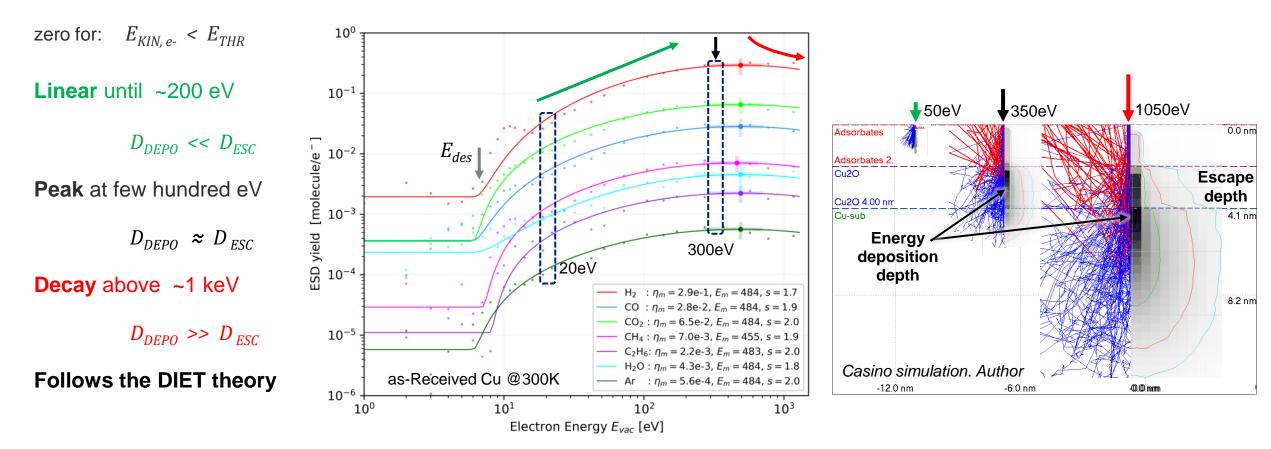




ESD energy dependence: Warm Cu

Main desorbing gases: H₂, CO, CO₂, CH₄, C₂H₆, Ar, H₂O

Threshold around 10eV

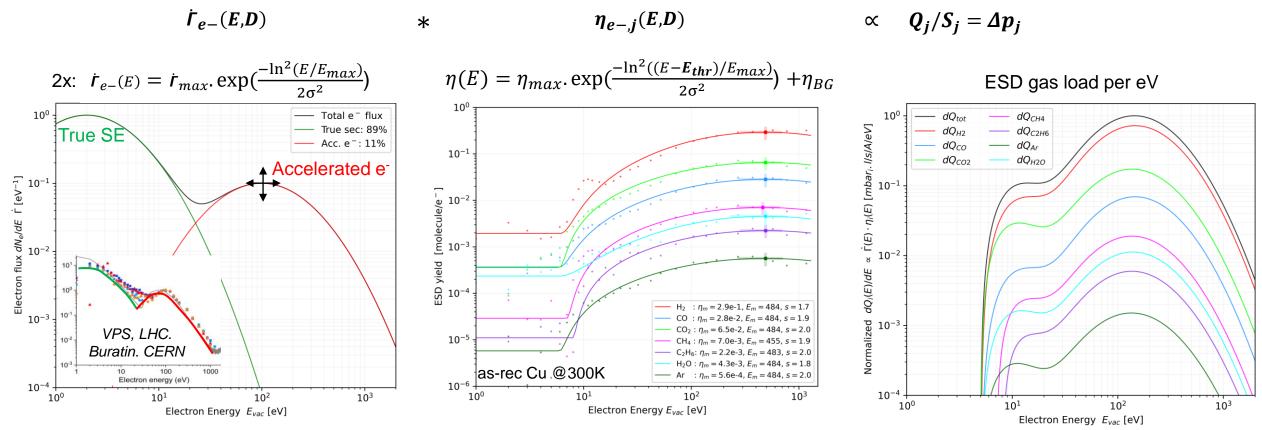




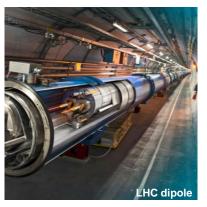
From SEY & ESD to Δp_i

Knowing the SEY ↔ EC ↔ ESD interplay allows calculating the dynamic pressure rise due to ESD

Most of Δp_j is caused by the beam-accelerated e



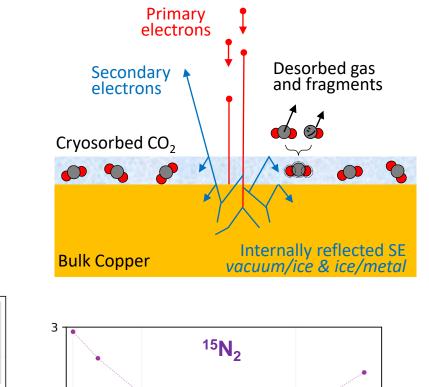


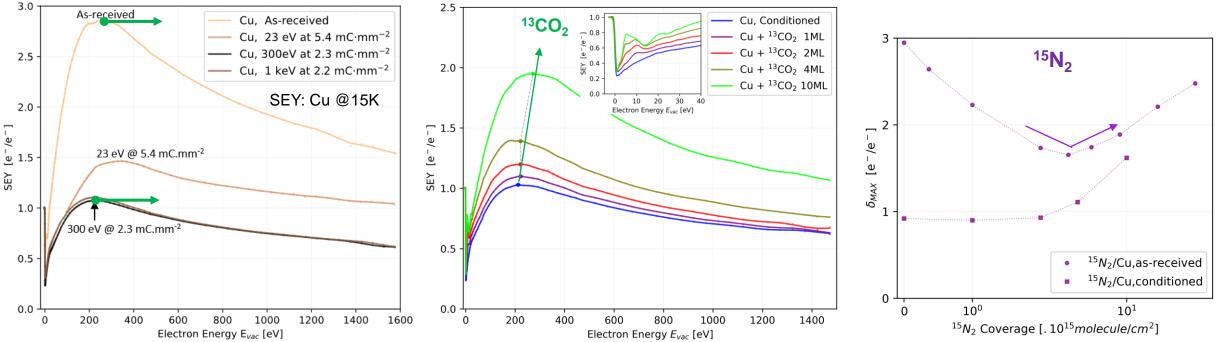


SEY: gas on conditioned Cu

Ice = cryosorbed gas, weakly-bound

SEY is substrate-agnostic @10ML (non-porous)







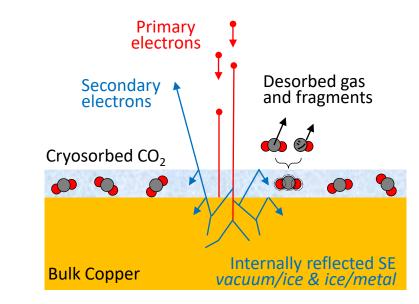
SEY: gas on conditioned Cu

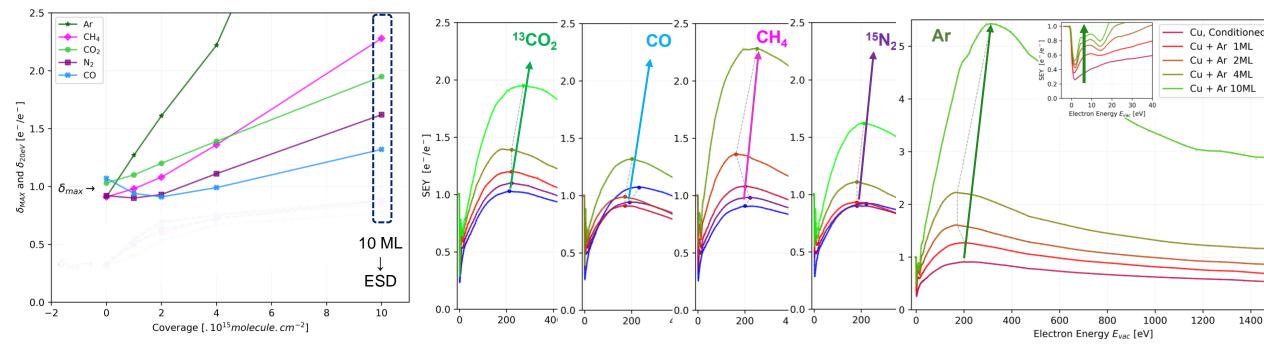
Ice = cryosorbed gas, weakly-bound

SEY is substrate-agnostic @10ML

LE-SEY is particularly sensitive, even low coverages Higher δ_{MAX} and $E_{MAX} \rightarrow e^-$ multipacting

Higher reflectivity at LE-SEY \rightarrow e⁻ survival \rightarrow faster EC build-up transients



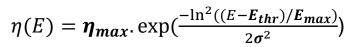


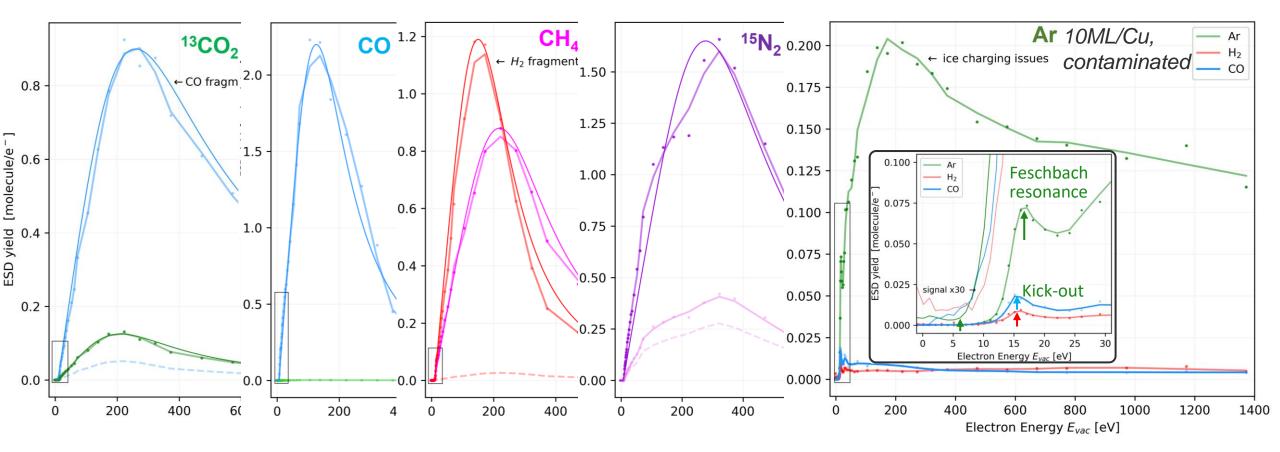


ESD of ices at 10ML

Ice = cryosorbed gas, weakly-bound

- \rightarrow high ESD yields
- \rightarrow significant cracking, induced by SE



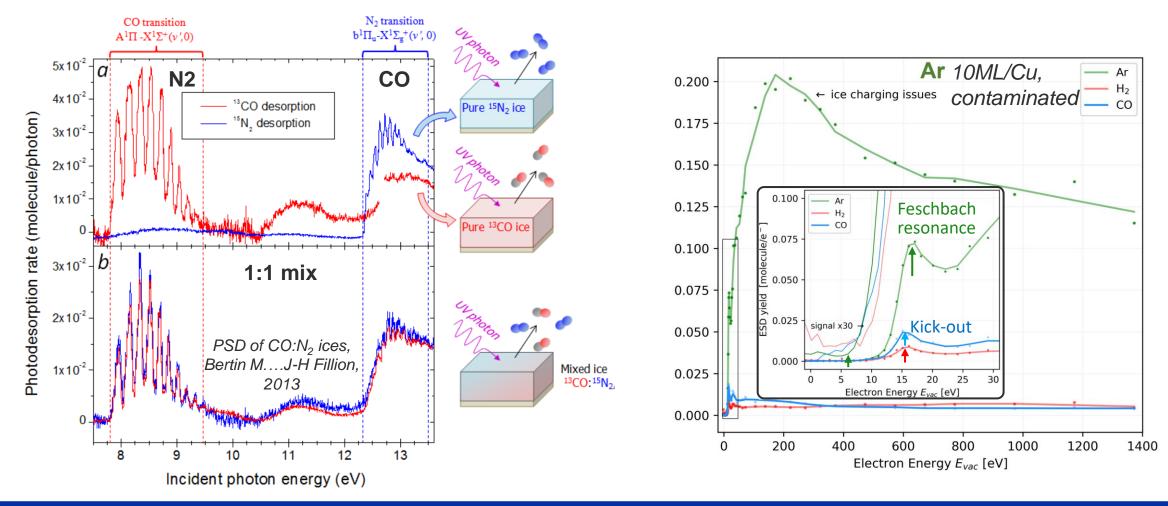




ESD of ices at 10ML

Mutual ESD yield influence in a mixture

Both enhancement and quench are possible





Binary ices: SEY & ESD at 10ML

Non-linear mapping of SEY & ESD with composition Linear averaging leads to factor ~2 errors

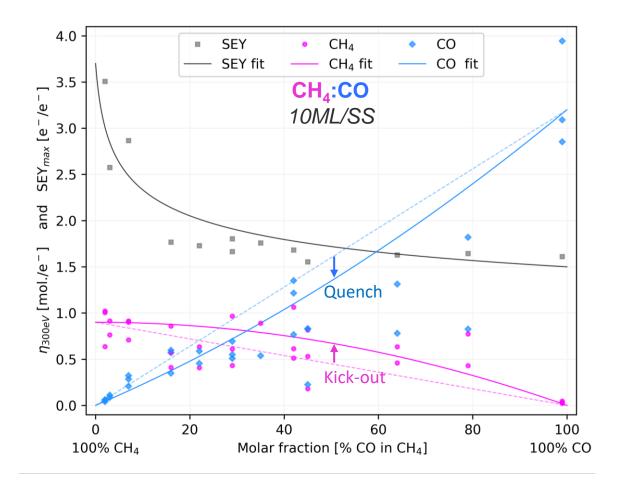
Mutual influence of desorption yields also observed in PSD:

 Bertin, M., Fayolle, E. C., Romanzin, C., Poderoso, H. A., Michaut, X., Philippe, L., ... & Fillion, J. H. (2013). Indirect Ultraviolet Photodesorption From CO: N2 Binary Ices—an Efficient Grain-gas Process. *The Astrophysical Journal*, 779(2), 120.

Quenching behaviour is also known:

- Dupuy, R., Haubner, M., Henrist, B., Fillion, J. H., & Baglin, V. (2020).
 Electron-stimulated desorption from molecular ices in the 0.15–2 keV regime.
 Journal of Applied Physics, 128(17), 175304.
- Reimann, C. T., W. L. Brown, and R. E. Johnson.
 Electronically stimulated sputtering and luminescence from solid argon.
 Physical Review B 37.4 (1988): 1455.

ESD and SEY often anticorrelate in thick ices (!)

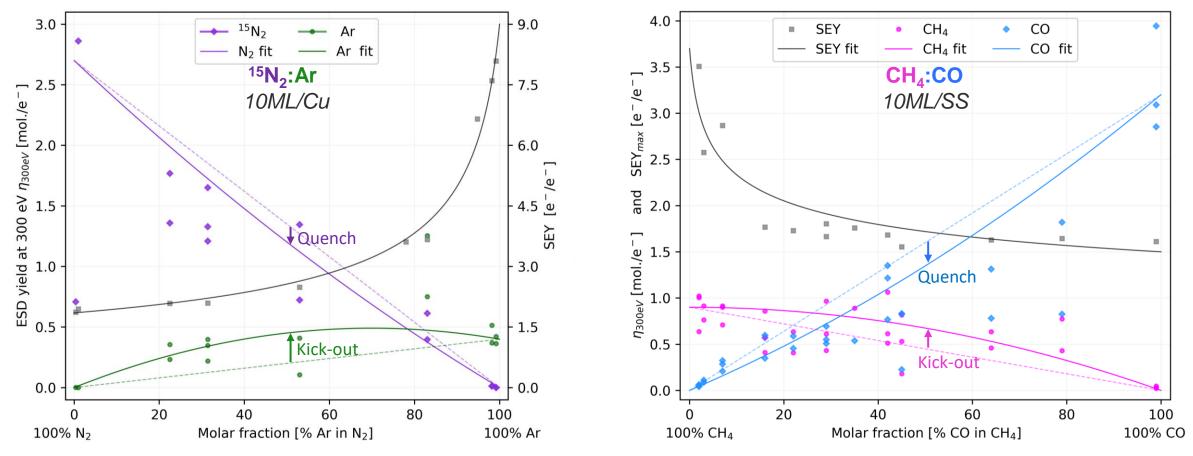




Binary ices: SEY & ESD at 10ML

Non-linear mapping of SEY & ESD with composition

Linear averaging leads to factor ~2 errors





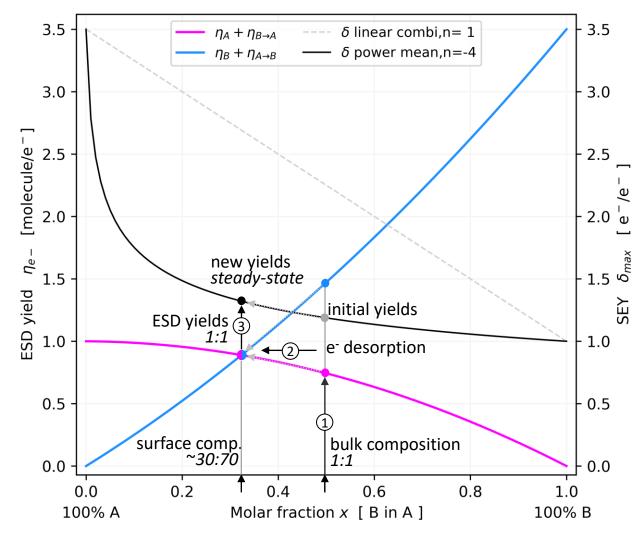
Binary ices: simple model for SEY & ESD

Simple model: $k\approx 0.5$, $n=3\sim 5$ SEY: $\delta_{A:B,max}(x) = \sqrt[n]{(x-1)} \cdot \eta^n_{A,max} + x \cdot \delta^n_{B,max}$ ESD: $\eta_{A:B\rightarrow A}(x) = (x-1) \cdot \eta_A + \eta_B \cdot x(x-1) \cdot \frac{\eta_B - \eta_A}{\eta_A + \eta_B} \cdot k^{sign(B-A)}$ $\eta_{A:B\rightarrow B}(x) = x \cdot \eta_B + \eta_A \cdot x(x-1) \cdot \frac{\eta_A - \eta_B}{\eta_A + \eta_B} \cdot k^{sign(A-B)}$

Possible generalization to n-components

If similar to multicomponent sputtering: (Ion Implantation and Synthesis of materials,Nastasi&Mayer,2006) e⁻ irradiation pushes the SEY and ESD to a new steady state, where the ESD yield ratio = bulk composition ratio

New SEY appears, following the newly established ESD ratio on the e⁻ irradiated thick ice surface.





Conclusions

New collector-based setup for cold ESD, SEY & TPD

Developed methods to probe low-energy region of ESD and SEY in conditions relevant to HL-LHC and other cold machines & applications

New data for technical-grade surfaces & coatings

ESD yield, threshold, conditioning rate and SEY as a function of energy, dose, temperature and cryosorbed gases for Copper and other materials, coatings & treatments

Insights into LHC vacuum and EC-induced dynamic vacuum effect: Conditioning is linked to ESD and SEY reduction, also at cold

Fraction of E-cloud effectively contributes to the conditioning

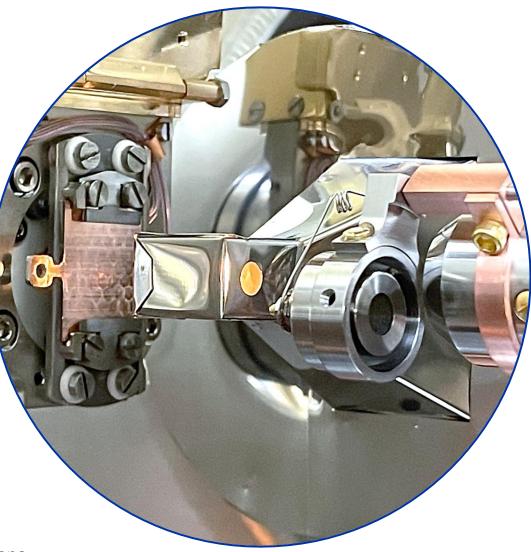
Electrons fragment molecules: different gas dynamics and chemistry

Mixed ices have a strongly nonlinear behavior

Next steps

Explore the parameter space and better understand the processes

Generalize the results for further use: semi-empirical fits to data for simulations





Acknowledgements



Research supported by the **HL-LHC project**

Researcher supported by CERN and CTU in Prague

Thanks to my colleagues for support

Thanks to the ECLOUD'22 organizers





CZECH TECHNICAL UNIVERSITY IN PRAGUE

Papers to read:



<u>Technical paper:</u> Haubner, Baglin, Henrist. (2022). Collector-based measurement of gas desorption and secondary electron emission induced by 0-1.4 keV electrons from LHC-grade copper at 15 K. *Accepted at NIM–B*.



First data paper: Haubner, Baglin, Henrist, (2022). Electron conditioning of technical surfaces

at cryogenic and room

temperature in the 0-1 keV energy

range. Accepted at Vacuum.



Thick Ices: Dupuy, R., Haubner, M., Henrist, B., Fillion, J. H., & Baglin, V. (2020). Electron-stimulated desorption from molecular ices in the 0.15–2 keV regime. Journal of Applied Physics, 128(17), 175304..



